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Introduction

About 14 years ago, when I organized the first International Symposium on Photoelectronic Detection and Imaging (ISPDI) in 1993 at the Friendship Hotel in Beijing, the symposium was going successfully. At the closing ceremony, I expressed my hope and desire to organize the symposium in China again. This year the day came, as we had a great honor to organize the International Symposium on Photoelectronic Detection and Imaging meeting in Beijing once again. It is truly a great pleasure for us to be able to greet our fellow scientists and experts from a number of countries; and I firmly believe this meeting will be a successful international event in the field of photoelectronic detection and imaging.

The purpose of ISPDI'07 is to provide a forum for the participants to disseminate and exchange ideas and to present up-to-date comprehensive assessments of progress and developments in the field of photoelectronic imaging and detection. To this end it is very gratifying to me that we have been assembled here for an informative exchange of opinions.

Collected in these five volumes of are close to 400 papers accepted for presentation at the symposium, contributed by over 1000 authors from more than 10 countries, including China, Japan, Russia, Germany, Netherland, India, United Kingdom, United States, Italy, and South Korea. These papers cover topics such as photoelectronic imaging, photoelectronic detection, opto-electronic system design, manufacturing and testing, imaging processing, related technology and applications, as well as many other aspects. These proceedings will no doubt benefit not only the participants of this meeting but also our colleagues engaged in research and development. It is sincerely hoped that as a consequence of this meeting research and development in photoelectronic detection and imaging will be promoted, and international cooperation between scientists and engineers who share this common interest will be enhanced.

Finally, on behalf of Prof. Wang Daheng, Prof. Jin Guofan and Prof. Yu Xin, China Ordnance Society and Beijing Institute of Technology, I would like to heartily thank our sponsors and supporters for all they have done for this meeting. Thanks also to all the authors for their contribution to these proceedings; to all of the participants and friends for their interest and efforts in helping us to make this symposium possible, especially those who have traveled great distances and taken their valuable time from their very busy schedules to attend the meeting, to the advisory and organizing committees for their effective work and valuable advice; and to all the organizations and individuals concerned for their active support and assistance, especially the Editorial Office of Optical Technique for their tireless effort and outstanding service in the administration and preparation of the manuscripts for the proceedings. I am also grateful to the SPIE staff for their support and collaboration in publishing these volumes.

Liwei Zhou
Topical Committee of Optics, China Ordnance Society